



## Drafts

BRS:

Pending

Active

- L1: (597) 438/680
- L2: (239) 438/663
- L3: (448) 438/770
- L4: (136) 438/773
- L5: (217) 438/775
- L6: (413) 438/756
- L7: (192) 438/757
- L8: (468) 438/743
- L9: (258) 438/744
- L10: (204) 438/786
- L11: (635) 438/787
- L12: (322) 438/791
- L13: (81) 438/954

Failed

Saved

- (1) selectively adj oxidizing adj2 silicon adj wafer
- (0) [batch adj type adj thermal adj oxidation adj furnace] and LPCVD and pad and oxide and inhibitor
- (5) [batch adj type adj thermal adj oxidation adj furnace] and LPCVD
- (5) [(batch adj type adj thermal adj oxidation adj furnace) and LPCVD ] and (pad or oxide or...
- (1) [selectively adj oxidizing adj2 silicon adj wafer] and (pad or oxide or dioxide or silico...
- (0) [batch adj type adj thermal adj oxidation adj furnace] and (oxidation adj inhibitor)
- (0) [batch adj type adj thermal adj oxidation adj furnace] and inhibit\$ and CVD
- (1) [oxidation adj inhibitor] and CVD and thermal and batch and furnace
- (1) [ [oxidation adj inhibitor] and CVD and thermal and batch and furnace] and (pad or oxide...
- (28) [oxidation adj inhibitor] and CVD and thermal
- (1) ["6335479"].PN.
- (1) ["6335479"].PN.) and (pad or oxide or dioxide or silicon or furnace or batch or oxidatio...

Favorites

Tagged (0)

UDC

Queue

Trash

6/20/02